

RESPONSE UNDER 37 CFR 1.116 EXPEDITED PROCEDURE EXAMINING GROUP 2851

PATENT APPLICATION

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

| In re Application of: |) Evenines D. Den Eenlin |
|--|-----------------------------|
| Shinichi HARA et al. | Examiner: D. Ben Esplin |
| Application No.: 09/818,625 | Group Art Unit: 2851 |
| Filed: March 28, 2001 |) |
| For: EXPOSURE APPARATUS, GAS REPLACEMENT METHOD, SEMICONDUCTOR DEVICE MANUFACTURING METHOD, SEMICONDUCTOR MANUFACTURING FACTORY, AND EXPOSURE APPARATUS MAINTENANCE METHOD | |
| Mail Stop AF | • |
| Commissioner for Patents | |

Commissioner for Patents P.O. Box 1450 Alexandria, VA 22313-1450

LETTER TRANSMITTING CORRECTED FORMAL DRAWINGS

Sir:

Transmitted herewith are two (2) formal drawing sheets, Figures 3 and 13, to be substituted for the corresponding drawing sheets currently on file in the above-identified application.

Figures 3 and 13 incorporate the changes requested by Applicants in a Request for Approval of Drawing Changes filed on February 28, 2003, which were subsequently approved by the Examiner in the Office Action dated March 21, 2003.

Applicants' undersigned attorney may be reached in our Washington, D.C. office by telephone at (202) 530-1010. All correspondence should continue to be directed to our address given below.

Respectfully submitted,

Attorney for Applicants

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